

- Drafts
- Pending
- Active
  - L1: (43959) nitride.clm. or (silicon adj nit)
  - L2: (678) 1 and ((anti adj reflective) or an
  - L3: (367) 2 and (nitride near layer)
  - L4: (239) 3 and (silicon near nitride).clm.
  - L5: (37) 4 and ((antireflective or (anti adj
  - L6: (38) 5 and (silicon adj rich)
- Failed
- (0) 2 near nitride
- Saved
  - (8) ("6475874") or ("6372561") or ("6365445")
  - (5) ("6524954") or ("6475874") or ("6316362")
  - (2) ("6107176") or ("6177335").PN.
  - (1) ("5633177").PN.
  - (17) ("4558507" | "4636822" | "4683645" | "4683646")
  - (2472) boron.clm. and gate.clm.
  - (0) (boron.clm. and gate.clm.) and (large ns)
  - (52) (boron.clm. and gate.clm.) and (implant)
  - (1) ("5633177").PN.
- Favorites

U	IPT #	Document ID	Date	Page	Title	Current OR	Current XM	Retrieval	Inventor	4	5	6	7	Image
1	US 6287951	20010911	17		Process for forming a combination hardmask and anti-reflective silicon nitride film using in-situ isolation using an anti-reflective coating	438/618	438/636		Lucas, Kevin D. et al.					US 628
2	US 6174644	20010116	6		Anti-reflective silicon nitride film using in-situ isolation using an anti-reflective coating	430/272.1	257/437		Shieh, Meng-Shiun et al.					US 617
3	US 6174590	20010116	19		Isolation using an anti-reflective coating	428/209	257/E21.55		Iyer, Ravi et al.					US 617
4	US 6121133	20000919	17		Isolation using an anti-reflective coating	438/636	257/E21.02		Iyer, Ravi et al.					US 612
5	US 5940598	19990907	17		Anti-reflective silicon nitride film using in-situ	430/311	257/E21.02		Shieh, Meng-Shiun et al.					US 594
6	US 5918147	19990629	14		Process for forming a semiconductor device with conductive interconnect	438/636	257/E21.02		Filipiak, Stanley M. et al.					US 591
7	US 5872385	19990216	8		Conductive interconnect structure and method of forming an integrated circuit part	257/437	257/413		Taft, Robert C. et al.					US 587
8	US 5639687	19970617	8		Method for forming an integrated circuit part	438/69	257/649		Roman, Bernard J. et al.					US 563
9	US 5539249	19960723	17		Method and structure for forming an integrated circuit part	257/649	257/437		Roman, Bernard J. et al.					US 553
10	US 5441914	19950815	8		Method of forming conductive interconnect	438/592	148/DIG.1		Taft, Robert C. et al.					US 544
11	US 5378659	19950103	7		Method and structure for forming an integrated circuit part	438/761	257/E21.02		Roman, Bernard J. et al.					US 537

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